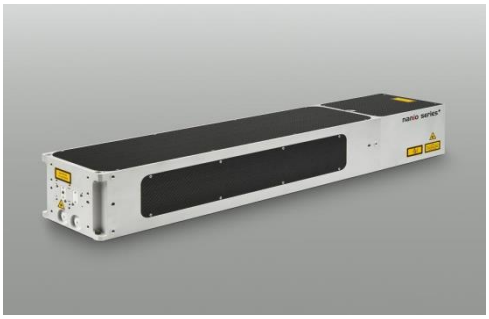
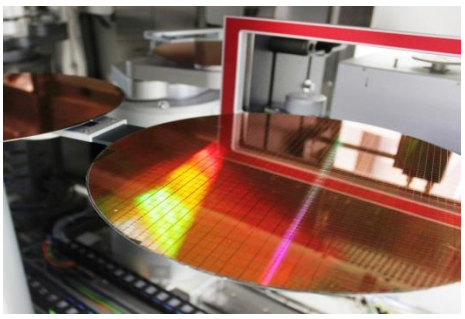
Data Sheet - IL C3000

The InnoLas **Wafer Marking System IL C3000**
for the unique Identification of your wafers





Address: InnoLas Semiconductor GmbH, Neubruch 2, 82266 Inning am Ammersee, Germany
Mail: sales@il-semi.com
Tel: +49 8143 24195-0

Wafer Marking

Data Sheet - IL C3000

Laser and Optics

Laser Type	Nd:YAG 355/532/1064 & CO_2 10.600nm
Laser Class	Class 1 / Class 4 with open cabinet
Focus Lens	F-Theta Objective
Galvo Head	High precision digitally controlled unit
Laser Stability	±1% peak to peak

Marking

Fonts	Dot Matrix SEMI OCR 5x9 / 10x18 / 15x27 Barcode SEMI BC412, IBM BC412 2D Code SEMI T7 Engraved Mode
Checksum	SEMI / IBM / customized (optional)
Serialization	Numeric / Alphanumeric / IBM
Text Position	Adjustable in X-, Y-Axis and Angle
Repeatability X and Y-direction	±75 µm (high precision) / ±100 µm (standard)
Dot Depth	0,1 – 100µm (depending on laser & material)
Dot Diameter	25 – 150 µm (depending on laser & material)

Handling System

Wafer Sizes	300 mm
Wafer Transfer	Single Arm Robot – Single End Effector
Wafer Alignment	Opto-mechanical
Wafer Handling	Vacuum / Edge Grip (optional)
Loading Stations	Up to 3
Throughput (wafers/hr)	120 (SEMI M12 spec. w/o reading)

Facility Requirements

Electrical	230 V (1P/1N/1PE) / 50 Hz / 16 Amps Optional: 115-200-240-370-380-400-420-480V
Power Consumption	1500 W
Communication	Ethernet RJ45 (SECS/GEM optional)
Vacuum	-800 mbar / 8mm OD connection
Exhaust	33,6 m^3/hr / 50 mm ID connection
CDA – Compressed Dry Air	6 bar / 8mm OD connection
PFO – Process Fluid Outlet	8mm OD connection
Cooling Water (optional)	> 5 l/min at 15°C
Water Pressure	2-6 bar
Weight	1200 kg
Dimension (w x l x h)	1648 x 2092 x 2196 mm

General

System Frame	Stainless Steel
System Panels	Powder coated
Mini Environment	ISO 3 (ISO 14644-1) / Class 1 (US FED STD 209E)
Certification	CDRH #0010530 / CE

Address: InnoLas Semiconductor GmbH, Neubruch 2, 82266 Inning am Ammersee, Germany
Mail: sales@il-semi.com
Tel: +49 8143 24195-0